

STATEMENT UNDER 37 CFR 3.73(b)

Applicant/Patent Owner: Hisao IGARASHI, et al.

New U.S. PCT Application Based on

Application No./Patent No.: PCT/JP05/06108

Filed/Issue Date: Herewith

Entitled: PROBE APPARATUS, WAFER INSPECTING APPARATUS PROVIDED WITH THE PROBE APPARATUS
AND WAFER INSPECTING METHOD

JSR Corporation

(Name of Assignee)

, a Corporation

(Type of Assignee, e.g., corporation, partnership, government agency, etc.)

States that it is:

1. ☒ the assignee of the entire right, title, and interest; or
2. ☐ an assignee of less than the entire right, title and interest.
- The extent (by, percentage) of its ownership interest is _____ %

in the patent application/patent identified above by virtue of an assignment from the inventor(s) of the patent application/patent identified above. A copy of the assignment is attached. The assignment was previously recorded or is being recorded concurrently herewith.

The undersigned (whose title is supplied below) is authorized to act on behalf of the assignee.

Surinder Sachar

Signature

Surinder Sachar
Registration No. 34,423

Sept. 22 2006

Date

Marvin J. Spivak

Printed or Typed Name

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